

Sectional Facilities, Electron Microscopy



Transmission Electron Microscope (TEM), Tecnai G² 30ST (FEI Company, USA)



TEM Specimen Preparation Equipment (Gatan Inc., USA)

Equipment:

- Ultrasonic Disk Cutter,
- Disk grinder.
- Dimple Grinder,
- Precision Ion Polishing System (PIPS),
- Precision Etching and Coating System (PECS),
- Plasma Cleaner (Ar/O₂ and H₂/O₂)



Scanning Electron Microscope (FESEM), LEO S430i (LEO, UK)



Field-Emission Scanning Electron Microscope (FESEM), Supra 35VP (Carl Zeiss, Germany)



SEM Sample Coating Units

- Gold Coating Unit (Edwards)
- Carbon coating unit (Hitachi, Emicon)
- Au/Pd coating unit (Polaron)



Atomic Force Microscope (AFM) Multiview 3000 (Nanonics Imaging Ltd., Israel)



RF Magnetron Sputtering Unit for Thin film deposition (Hindhivac Ltd., India)